Docket No.: OGOSH46USA

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE.

Application No.

: 10/567,729

Confirmation No. 7682

Applicant

Kazutoshi Kojima et al.

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371 Filed

February 1, 2006

Art Unit

2814

Examiner

: Sarah Kate Salerno

Customer No.

00270

Title

SILICON CARBIDE EPITAXIAL WAFER, METHOD FOR PRODUCING SUCH WAFER, AND SEMICONDUCTOR

DEVICE FORMED ON SUCH WAFER

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## AMENDMENT

Sir:

This is an Amendment in response to the non-final Office Action dated February 21, 2008. A Petition for a One Month Extension of Time is being filed herewith to extend the deadline for response from May 21, 2008 to June 21, 2008. Kindly amend the application as set forth below.

Amendments to the Specification begin on page 2 of this paper.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this paper.

Amendments to the Drawings being on page 6 of this paper and include three attached replacement sheets.

Remarks/Arguments begin on page 7 of this paper.